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Bib Data Sheet

<b>SERIAL NUMBER</b> 10/814,303	<b>FILING OR 371(c) DATE</b> 04/01/2004 <b>RULE</b>	<b>CLASS</b> 430	<b>GROUP ART UNIT</b> 1756	<b>ATTORNEY DOCKET NO.</b> 04329.3300
<b>APPLICANTS</b> Takashi Sato, Fujisawa-shi, JAPAN; Shoji Mimotogi, Yokohama-shi, JAPAN; Shigeru Hasebe, Yokohama-shi, JAPAN;				
<b>** CONTINUING DATA *****</b>				
<b>** FOREIGN APPLICATIONS *****</b> JAPAN 2003-101063 04/04/2003				
<b>IF REQUIRED, FOREIGN FILING LICENSE GRANTED</b> <b>** 06/16/2004</b>				
Foreign Priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance Verified and Acknowledged _____ Examiner's Signature _____ Initials _____		<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWING</b> 4	<b>TOTAL CLAIMS</b> 20
			<b>INDEPENDENT CLAIMS</b> 8	
<b>ADDRESS</b> Finnegan, Henderson, Farabow, Garrett & Dunner, L.L.P. 901 New York Ave, N.W. Washington, DC20001				
<b>TITLE</b> EXPOSURE METHOD, EXPOSURE QUANTITY CALCULATING SYSTEM USING THE EXPOSURE METHOD AND SEMICONDUCTOR DEVICE MANUFACTURING METHOD USING THE EXPOSURE METHOD				
<b>FILING FEE RECEIVED</b> 1630	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue ) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	